Appl. No. 10/618,067

Resp. Dated January 15, 2008.

:

Reply to Office Action of November 16, 2007.

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No.

10/618,067

Confirmation No. 4314

Applicant

Jifa Hao, et al.

Filed

July 11, 2003

Art Unit: 2822

SENSITIVITY TO DEPOSITION AND ETCH PROCESSING

Title

DENSE TRENCH MOSFET WITH DECREASED ETCH

Examiner

Rose, Kiesha L.

Docket No. :

3016429 (17732.6357.003)

Customer No.:

44,331

Mail Stop: AF

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

RESPONSE TO OFFICE ACTION

Sir:

Responsive to the November 16, 2007 final Office Action, Applicants submit the following Remarks:

Remarks begin on page 2 of this paper.